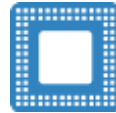


# Development and Exploitation of Processes For Thin Flexible Glass

Wednesday 14<sup>th</sup> May 2014



**ATOTECH**



# Plating on Glass



**ATOTECH**

Electronics

# Plating on Glass

## Overview and Process Technologies

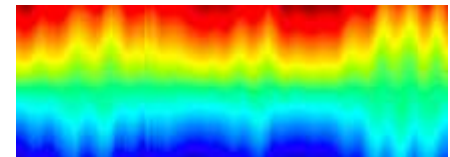
2014.05.13\_PoG\_Overview MSolv\_ART



# Plating on Glass

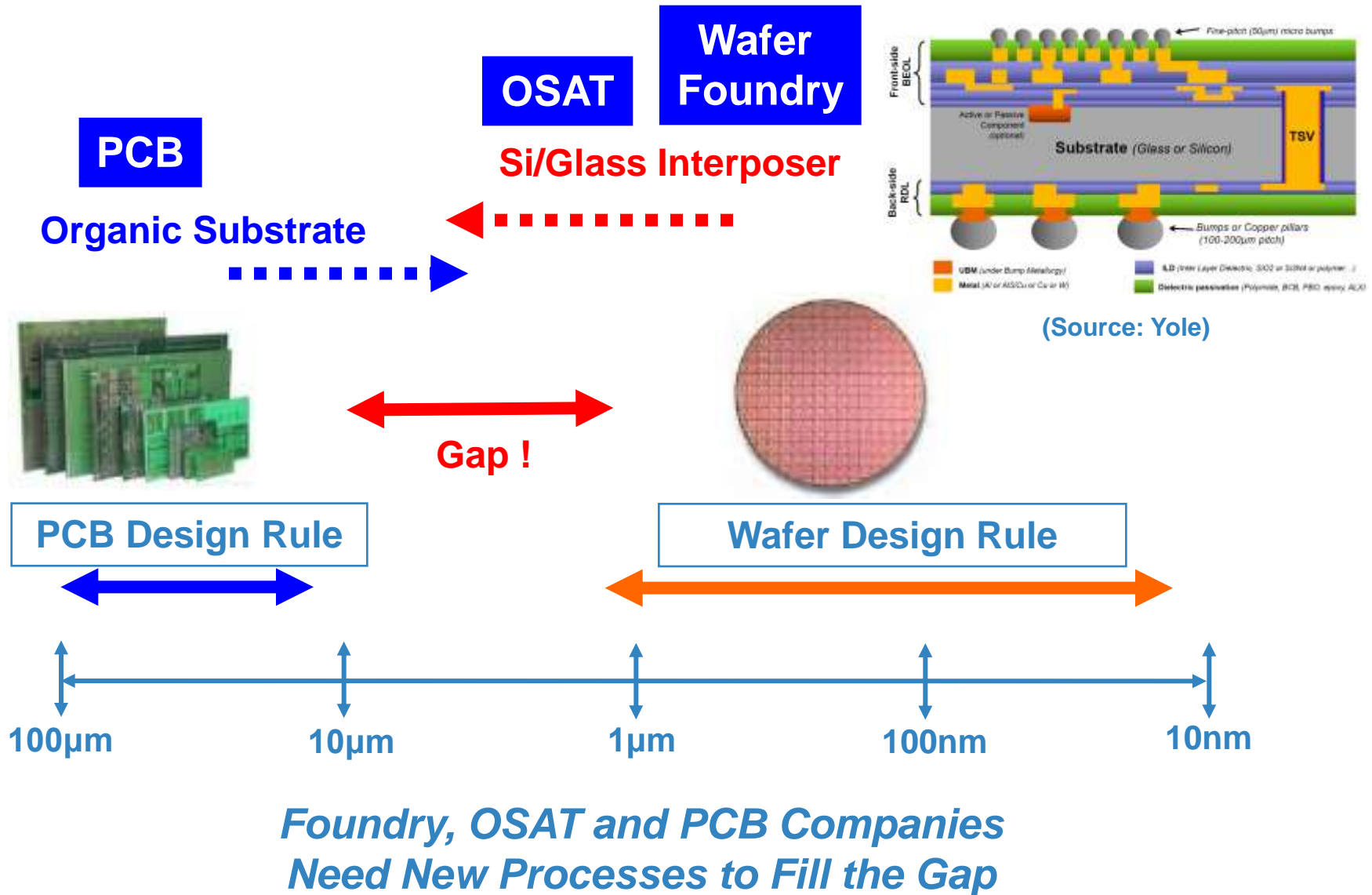
## Scope

- Market Trends / Motivation
- Applications
- Manufacturing Methods
- Through Hole Filling
- Electrical Characterization
- Summary



# Plating on Glass

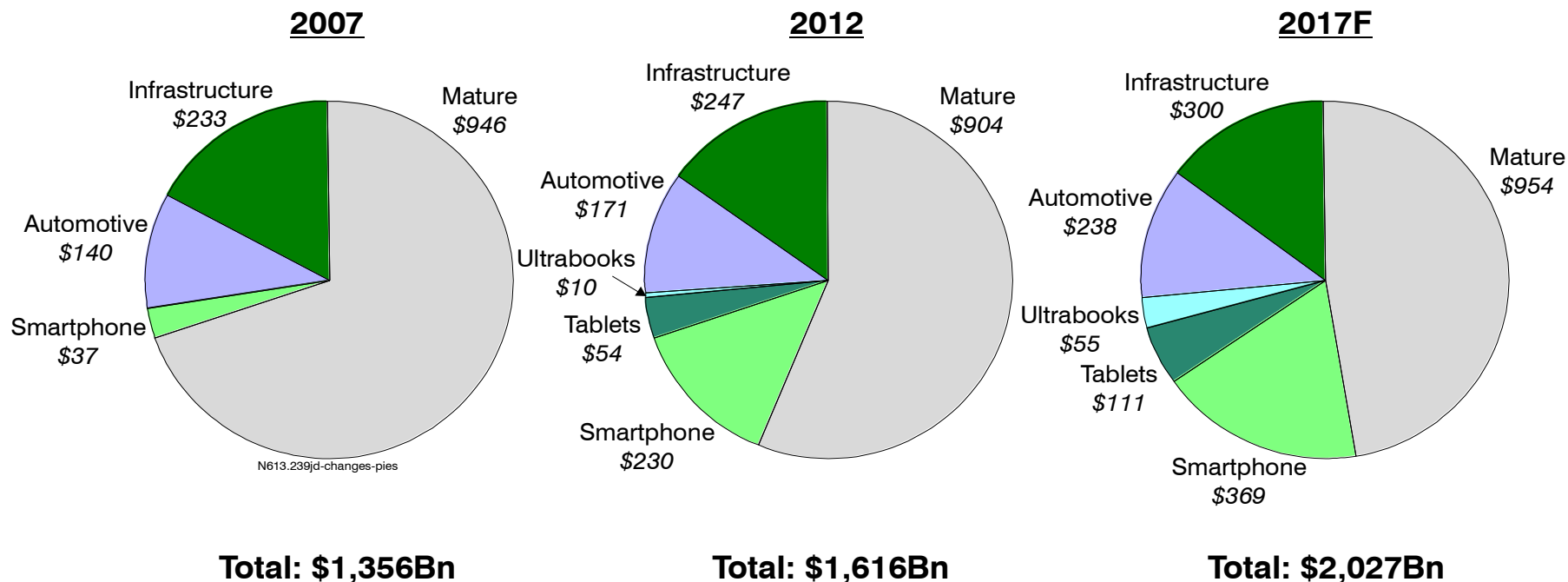
## Market Trends - Electronics Evolution



# Plating on Glass

## Market Trends

### CHANGES IN THE ELECTRONICS INDUSTRY STRUCTURE



	CAAGR 2007-2012	CAAGR 2012-2017	CAAGR 2007-2017
Mature	-0.9%	1.1%	0.1%
Growth	11.8%	8.5%	10.1%
Total	3.6%	4.6%	4.1%

**Major Growth Areas in Mobile Formats – Smartphone – Tablets**



# Plating on Glass

## Market Trends

- Major growth is all in mobile sector
- Smartphone growth:
  - 2012 - 2013 -15.7%
  - CAGR 2012 - 2017 - **9.9%**
- Tablet growth:
  - 2012 - 2013 - 46.3%
  - CAGR 2012 - 2107 - **15.6%**
- Ultrabook growth:
  - 2012 - 2013 - 80.1%
  - CAGR 2012 - 2017 - **40.6%**
- Servers and Automotive will see steady growth
  - Cloud computing and automotive electronics



Apple iPhone 5S



Apple iPad Mini

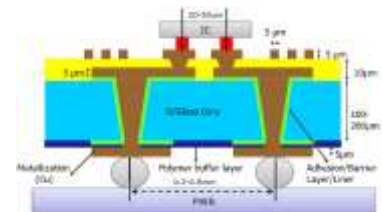
- Rest of Electronics Industry will stagnate

***Major Growth Areas in Mobile Formats – Smartphone – Tablets***

# Plating on Glass

## Motivation

- TFT Metallization for Flat Panel Displays
  - Sputtered seed layers (Mo, Ti/Cu)
  - Electroless Copper deposition (Up to 2  $\mu\text{m}$ )
  - Electrolytic Copper plating (2 – 20  $\mu\text{m}$ )
- Metallization for Touch Screens
  - Electroless Copper for improved conductivity
- Glass Metallization for Photovoltaic Applications
  - Electroless Copper on plain glass
  - Backplane electrode metallization
- Glass Metallization for Advanced Chip Packaging
  - Sputtered seed layers (Ti/Cu) or plain glass
  - Adhesion promoters for direct plating of electroless
  - Electroless and Electrolytic Copper for Glass interposer



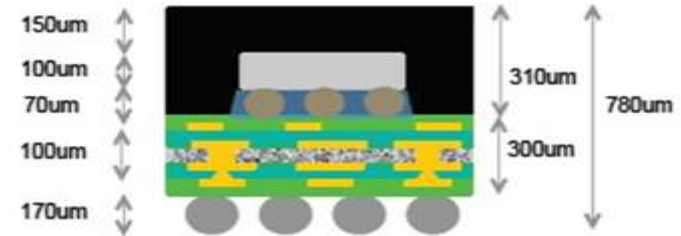
Source: PRC at Georgia Tech



# Plating on Glass

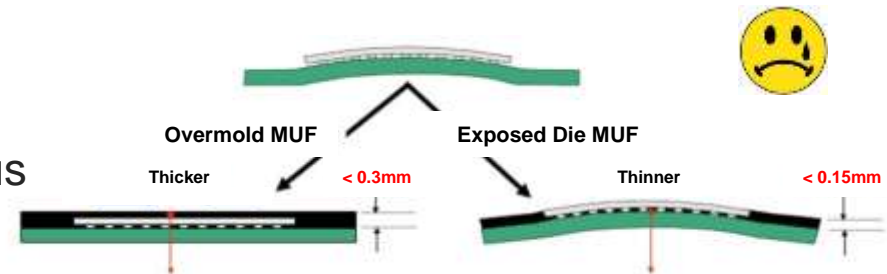
## Motivation

- Mobile Device Packaging
  - Handset thickness approaching 6mm
  - Battery and screen size increasing
  - Chip packaging and the substrate board must shrink to accommodate this



**Solder Balls Significant Proportion of Package Height**

- Warpage Reduction
  - Core thickness, CTE and modulus key
  - Core CTE already at 3ppm
    - Further reduction is no longer an option
  - Industry needs materials of higher modulus



**Low Cry Warpage Essential for Thinner Packages**

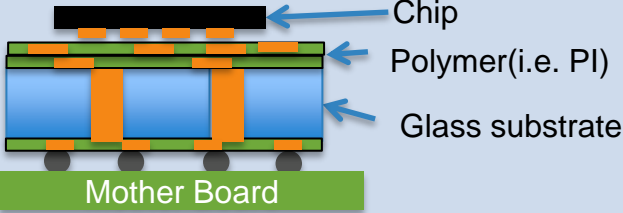
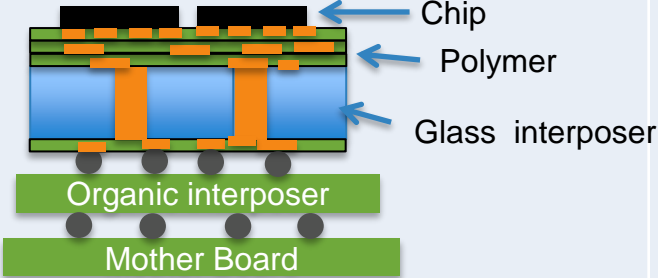
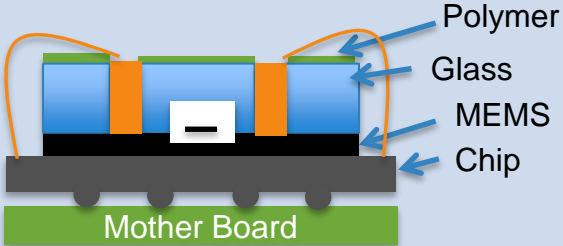
Source: Qualcomm

- Pitch Requirement Reducing
  - Fine pitch requires copper pillar connections
  - Thermocompression bonding essential
  - Thinner Molding Compound increases warpage
  - Higher Mold shrinkage and modulus also required

MUF – Molded Underfill

# Plating on Glass

## Possible Applications

Category	Structure	Application
Glass substrate	 <p>Chip Polymer(i.e. PI) Glass substrate Mother Board</p>	RF module
Interposer	 <p>Chip Polymer Glass interposer Organic interposer Mother Board</p>	2.5/3D packaging
3D WLP	 <p>Polymer Glass MEMS Chip Mother Board</p>	MEMS



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# Manufacturing Methods

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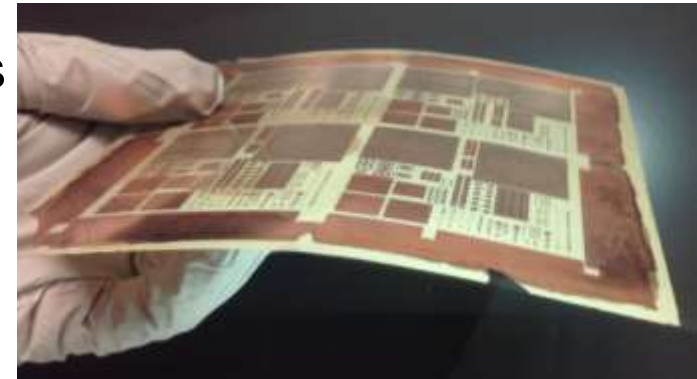


# Plating on Glass

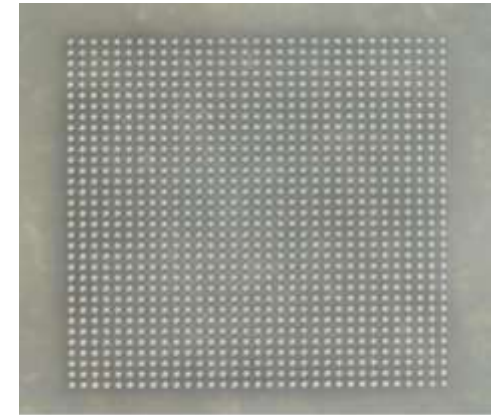
## Manufacturing Methodologies

- Sputtering of seed layer directly onto glass
  - Aspect ratio issues
  - Variable adhesion
- Nano Particle Inks
- Polymer Laminated Glass
  - Georgia Tech Consortia
- VitroCoat Adhesion Promoter
  - Metal Oxide based adhesion promoter
  - Suitable for glass and ceramics

(Source: Georgia Tech)



30µm Thick Polymer Laminated Glass



1089 Via Drilled Simultaneously

(Source: Asahi Glass Company)

***Adhesion Improvement by Additive Roughening Processes***



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# Sputtered Seed Layer

Electronics

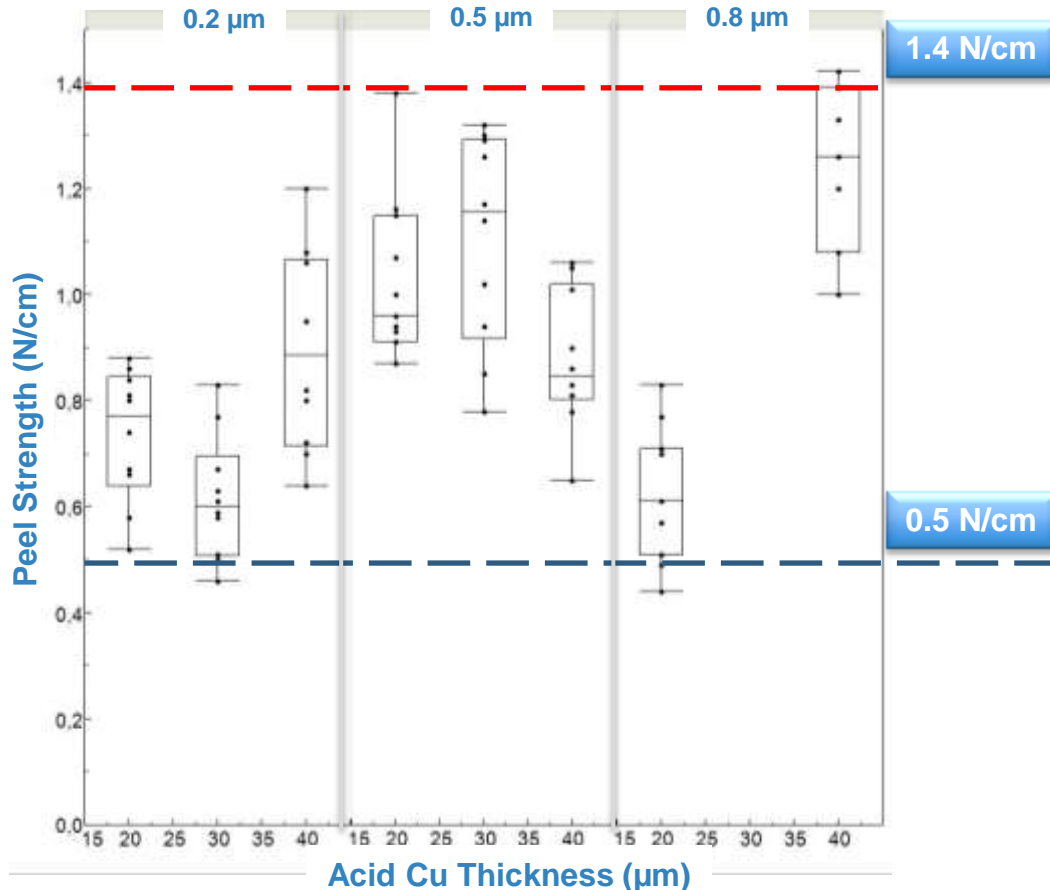


# Plating on Glass

## Sputtering - Peel Strength on Glass

### Integration into Interposer Manufacturing Process – Benchmark Peel Strength

Sputtered Ti/Cu Seed Layer thickness



### Limitations of Sputtered Seed Layers for Adhesion on Glass

- Low adhesion regardless of seed layer thickness (0.4 – 1.4 N/cm)
- Tendency to delaminate for thick copper layers
- Difficult to sputter in high aspect ratio through holes for glass substrates

**Sol Gel Exhibits Higher Peel Strength Than Sputtered Layers**





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# Nano Particle Inks

Electronics

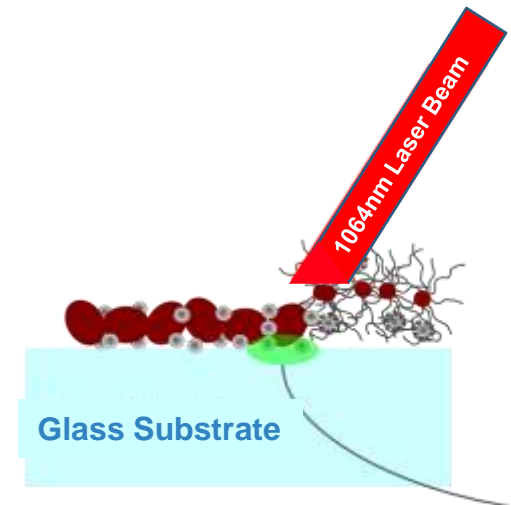
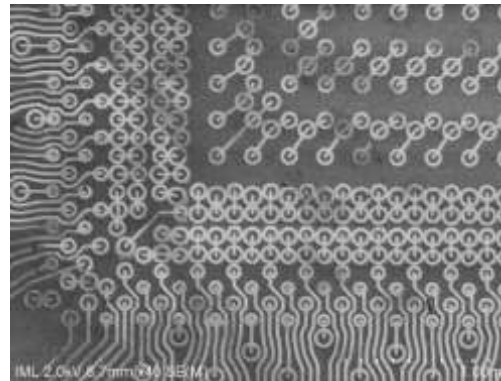
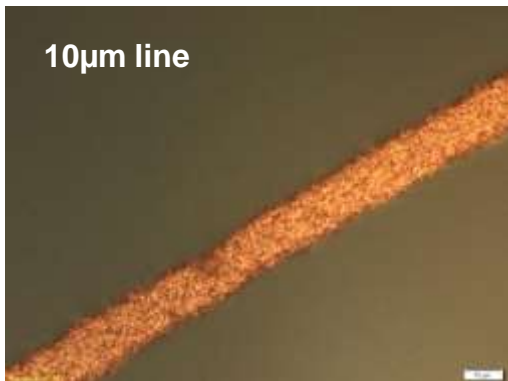


# Plating on Glass

## Adhesion Promoters for Glass

- Cleaning of the glass is crucial to obtain OH- rich surface
- Material is sprayed onto the glass
- Laser fixing creates covalent bonding with the glass
- Direct laser write or full glass coverage possible
- Wash off surplus if required
- Electroless copper is auto catalytically deposited

### Early Prototype Structures



***Adhesion Sufficient to Cause Cohesive Failure Mechanism in the Glass!***



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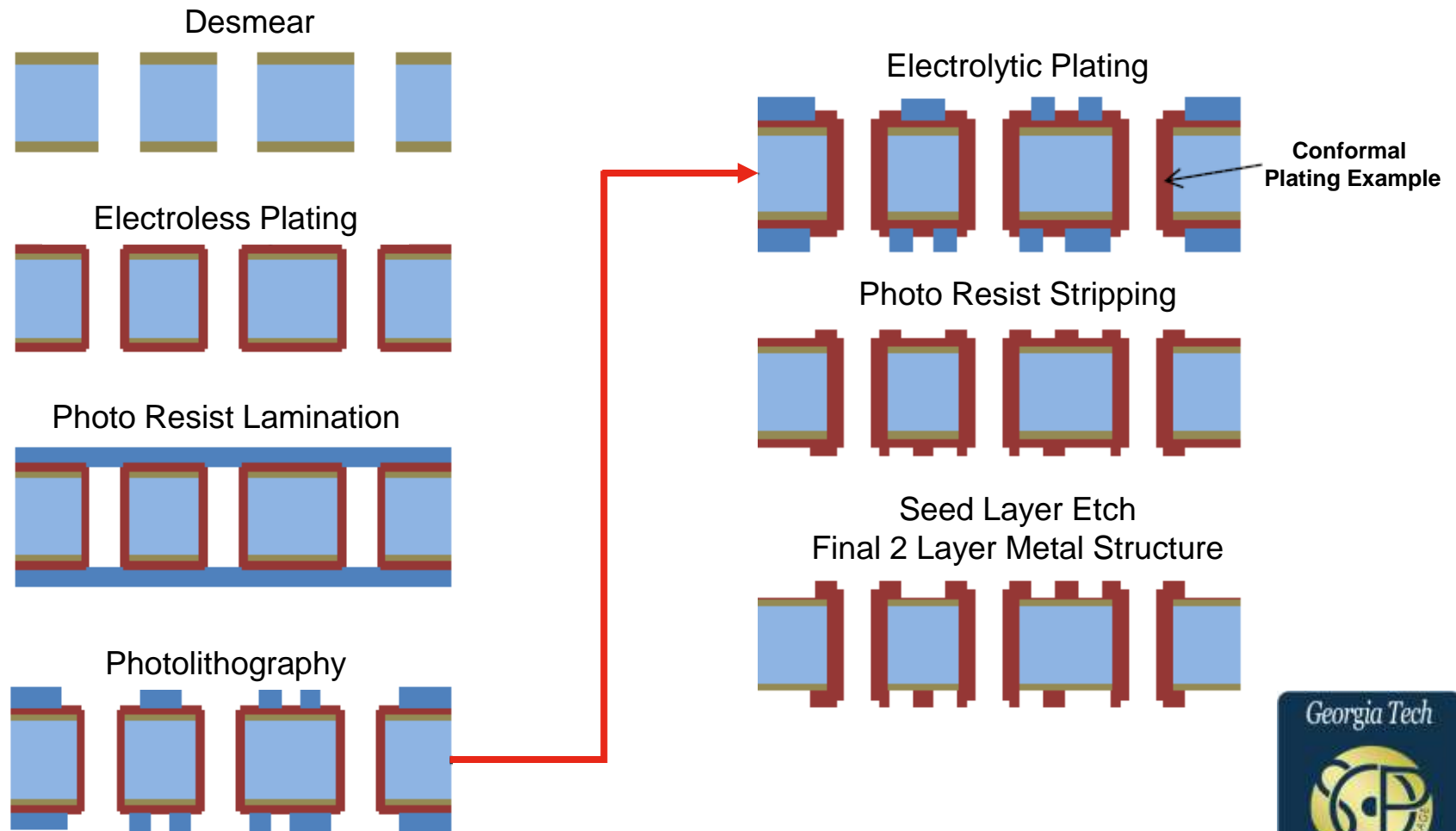
# Polymer Laminated Glass

Electronics



# Plating on Glass

## Polymer Laminated Glass



### *Process Sequence for a Two Layer Metal Structure*





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# Metal Oxide Adhesion Promoter

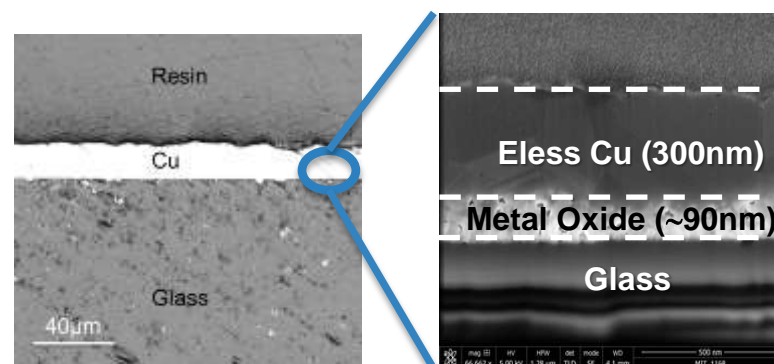
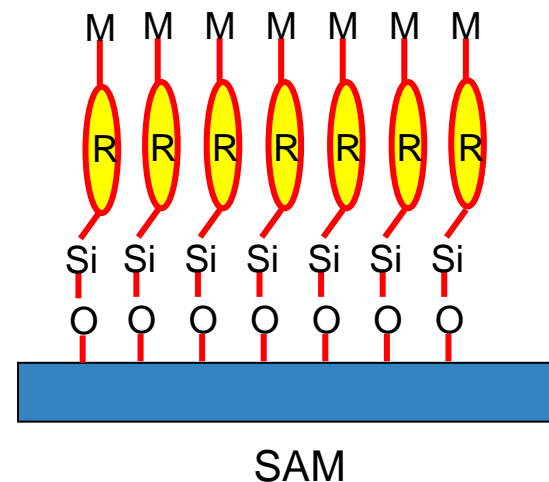
Electronics



# Plating on Glass

## Introduction

- Targets
  - Replace sputtering by wet chemical process for Glass, Si/SiO<sub>2</sub> and Ceramic plating
  - Target > 5N/cm adhesion
- Approaches
  - Sol-Gel coating with metal oxide intermediate layer
  - Covalent bonds with Self Assembled Monolayer (SAM)
  - PhD project at CWRU

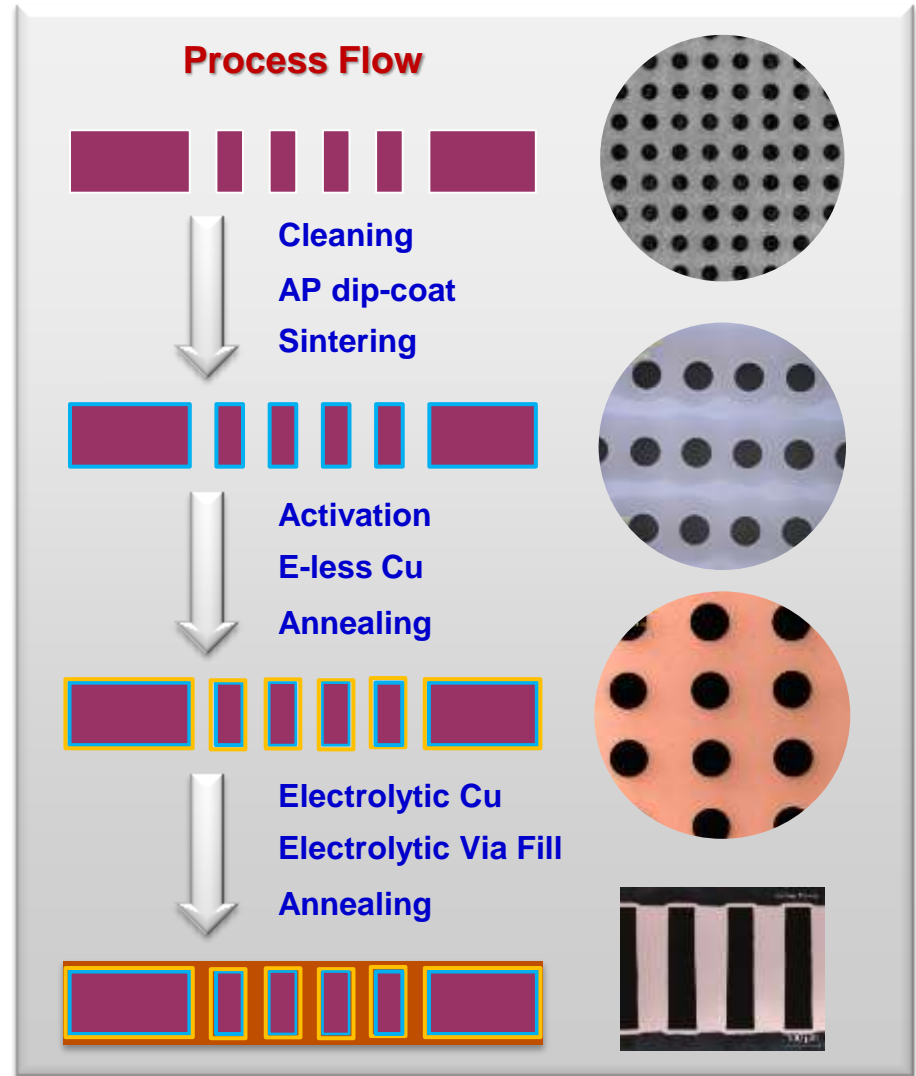




# Plating on Glass

## Process Flow for Plating on Glass with VitriCoat

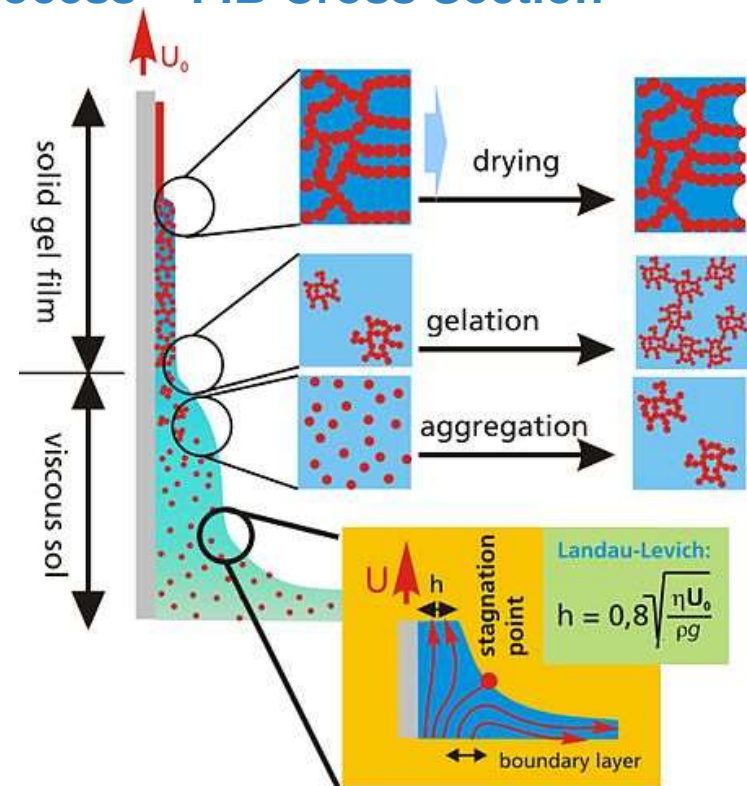
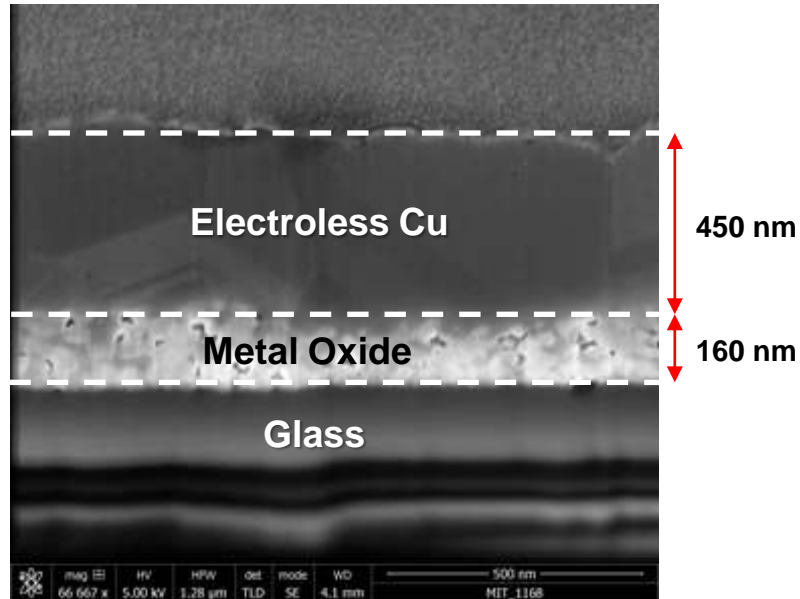
- Glass Cleaning
- Apply Adhesion Promoter
  - Metal Oxide Based
- Sintering
- Electroless Copper
- Electrolytic Cu Reinforcement
- X-Bridging
- Via Filling



# Plating on Glass

## Adhesion Promoter Thickness Control

### Metal Oxide Intermediate Layer - Sol Gel Process – FIB Cross Section



Principle of Sol Gel Process (Dip Coating)

- The thickness of the metal oxide layer is tunable
- Nano scale mechanical anchoring and chemical bonding

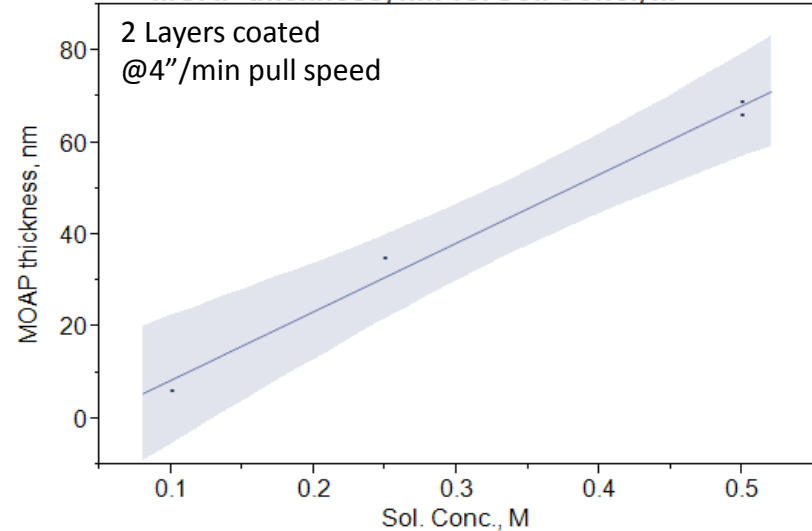
***Adhesion Improvement by Additive Roughening Processes***

# Plating on Glass

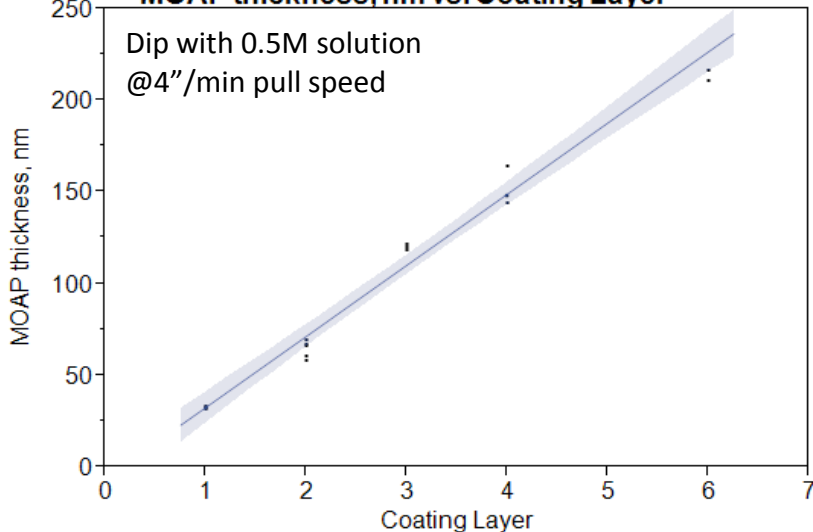
## Adhesion Promoter Thickness Control

- The thickness of the metal oxide layer can be controlled by
  - Concentration of solution
  - Pull speed
  - Number of coating layers

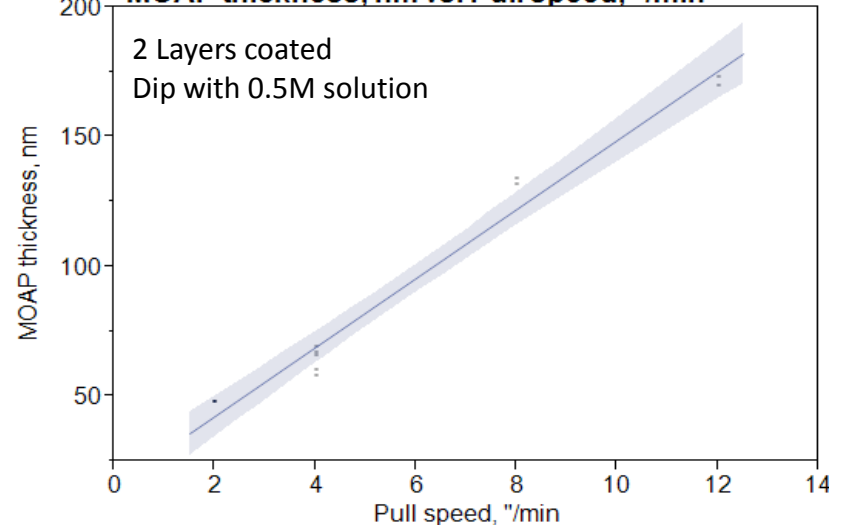
**MOAP thickness, nm vs. Sol. Conc., M**



**MOAP thickness, nm vs. Coating Layer**



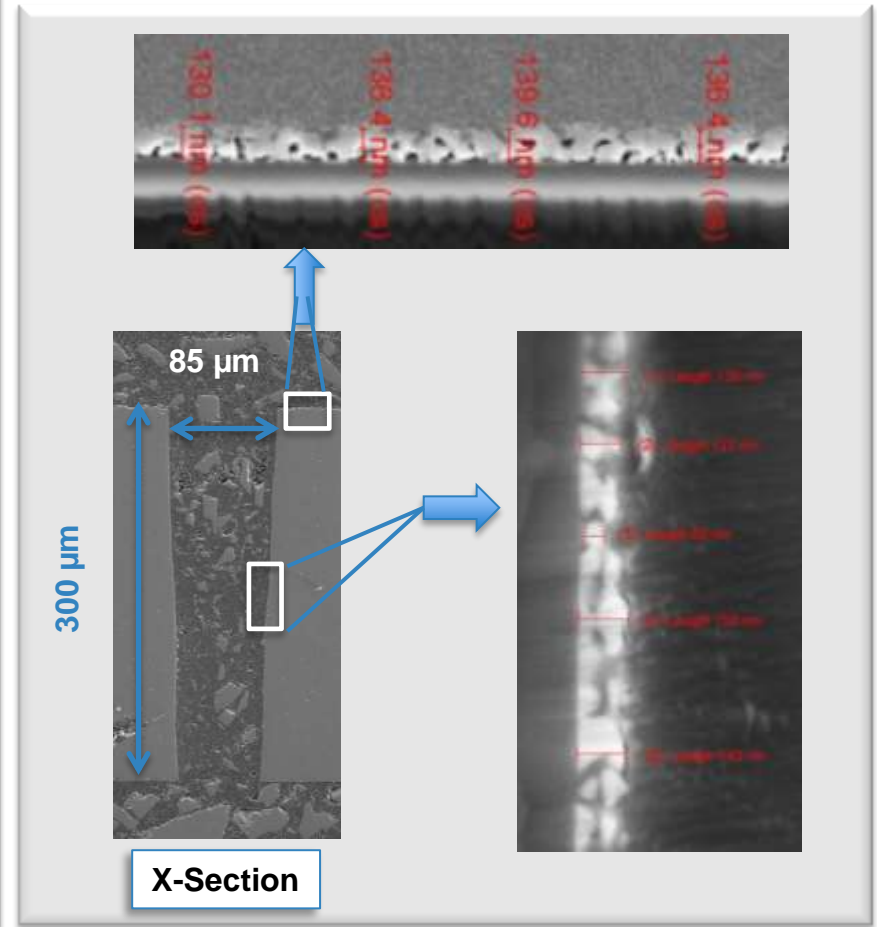
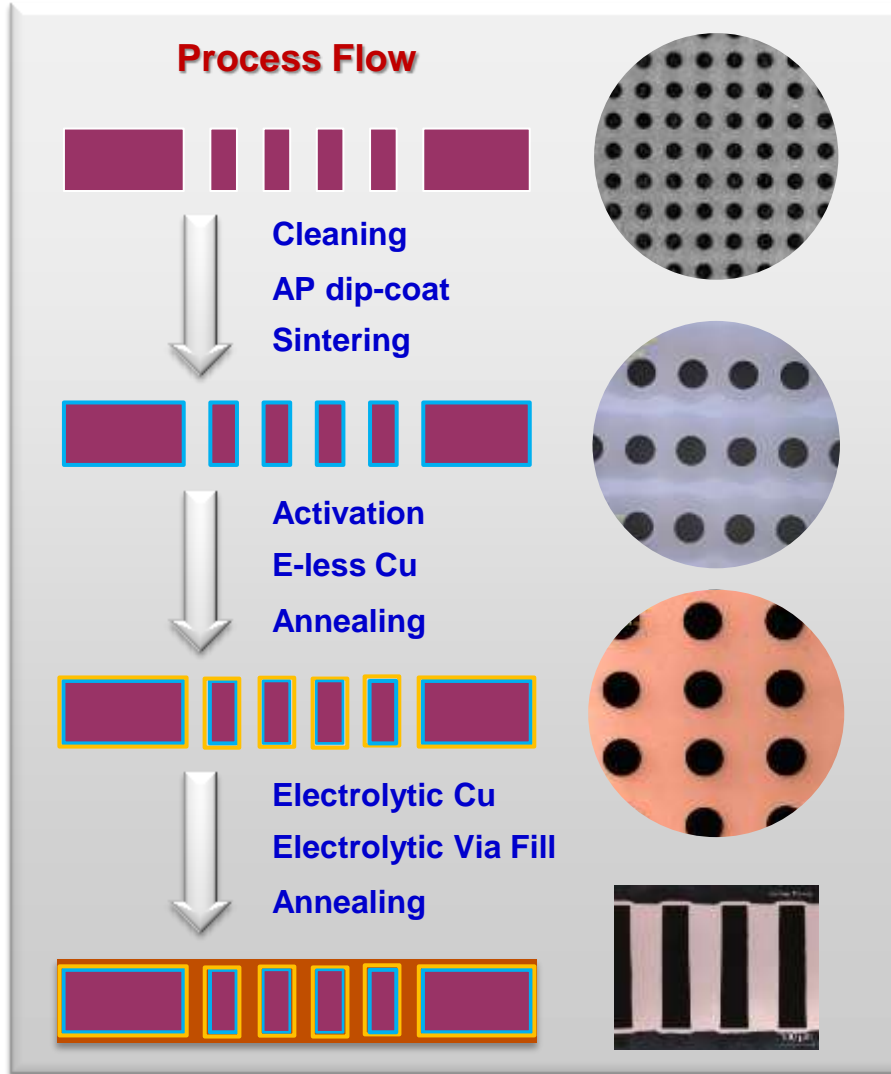
**MOAP thickness, nm vs. Pull speed, "/min**



# Plating on Glass

## Electroless Copper and Electrolytic Copper Plating

- AP coating on the surface and inside the via hole



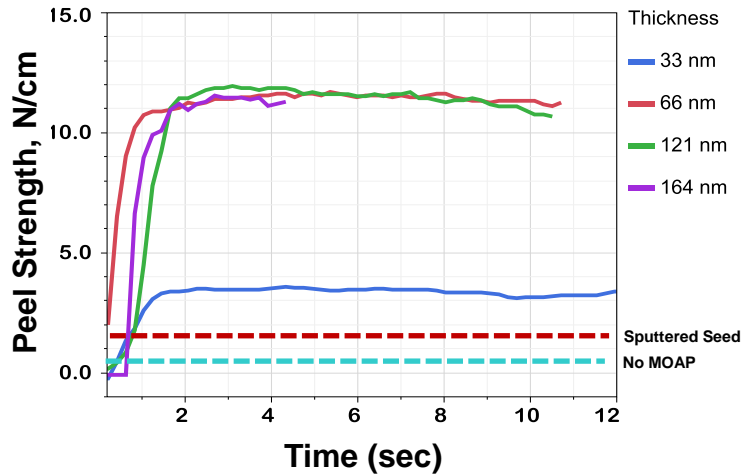
# Plating on Glass

## Peel Strength Versus Adhesion Promoter Thickness

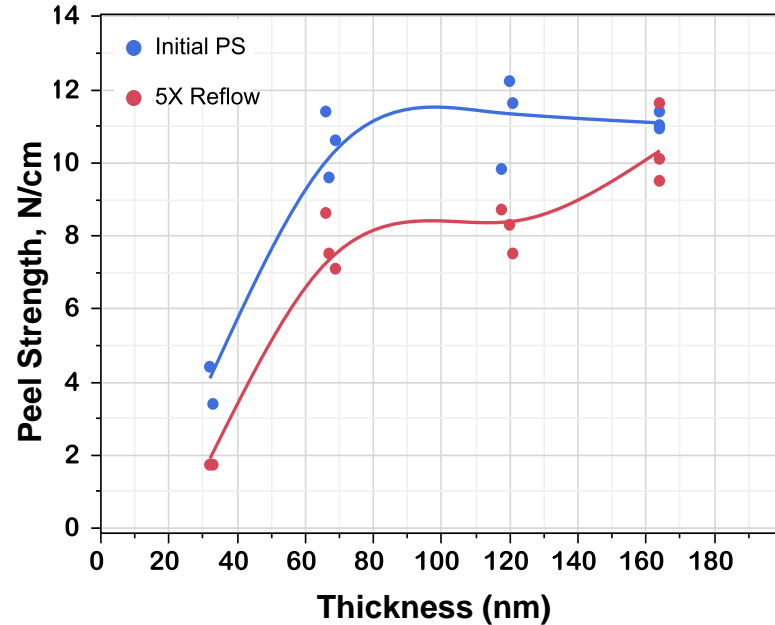
Asahi Glass

15 $\mu$ m Cu thickness

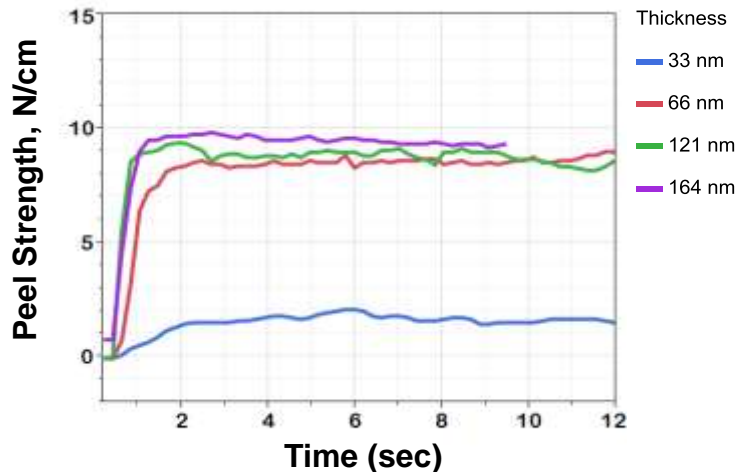
Initial Peeling Profile



Peel Strength vs. AP Thickness



5X RF Peeling Profile



5  $\mu$ m Cu w/o AP



15  $\mu$ m Cu w/ AP

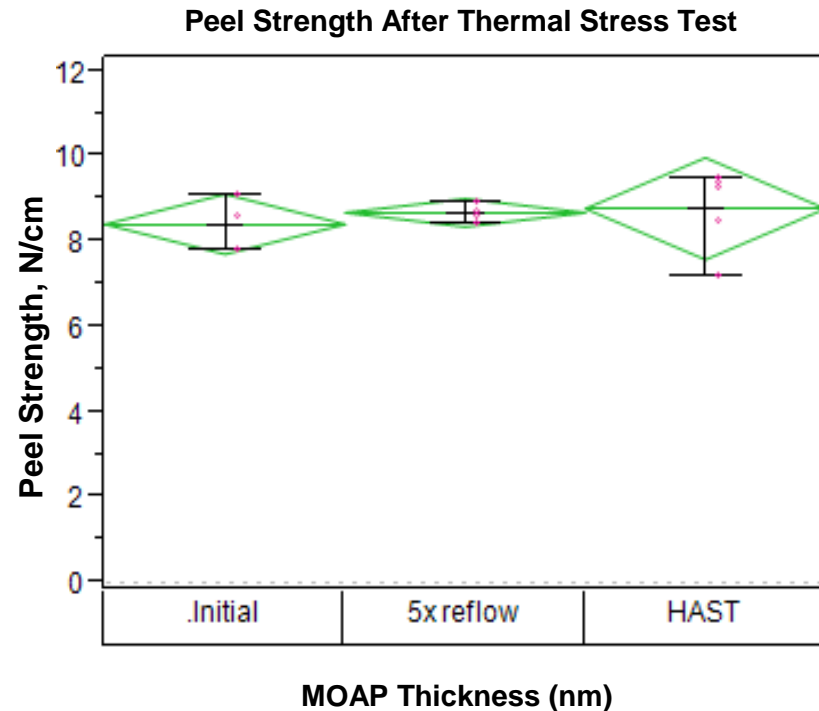
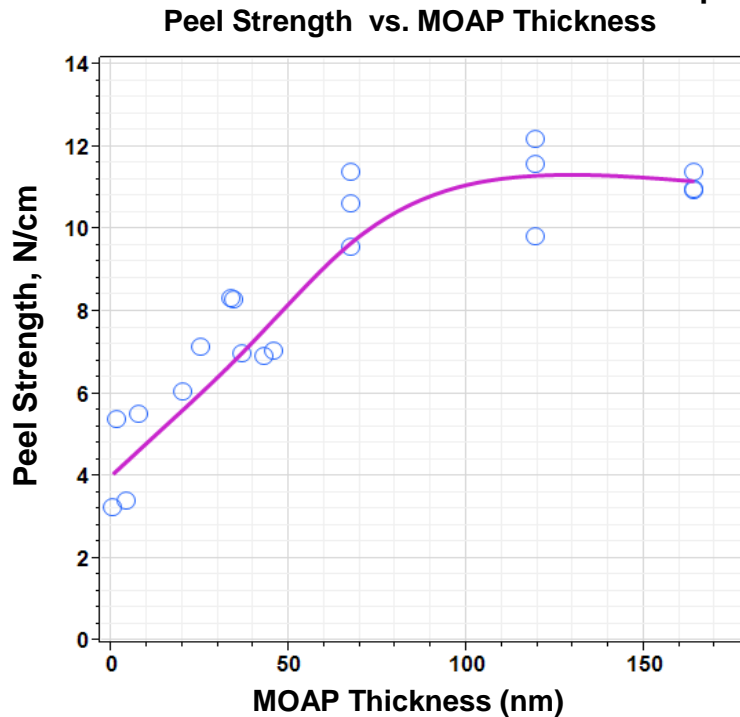


# Plating on Glass

## Peel Strength Versus Adhesion Promoter Thickness

Corning Glass

15 $\mu$ m Cu thickness



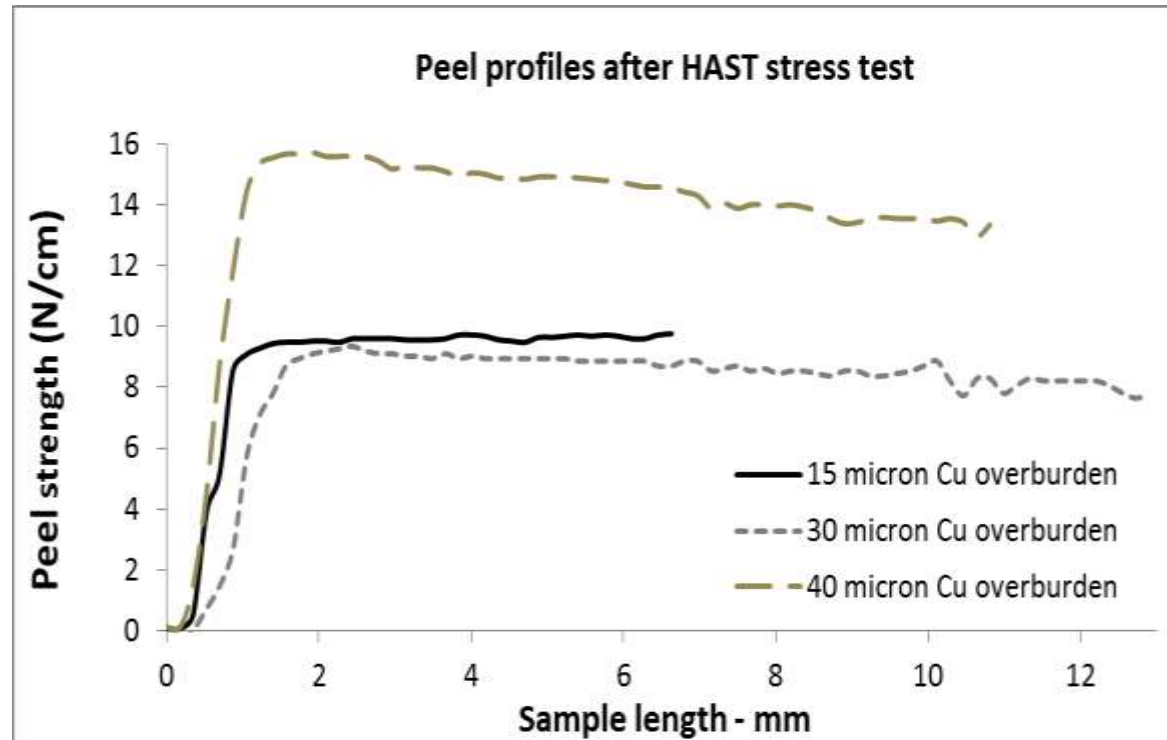
- Clear dependence of peel strength on AP thickness
- Peel strength of 5-6 N/cm achieved with ~ 10nm AP thickness
  - Fine line patterning benefits
- No significant impact of thermal excursion on performance



# Plating on Glass

## Peel Strength vs. Copper Thickness

Corning Glass

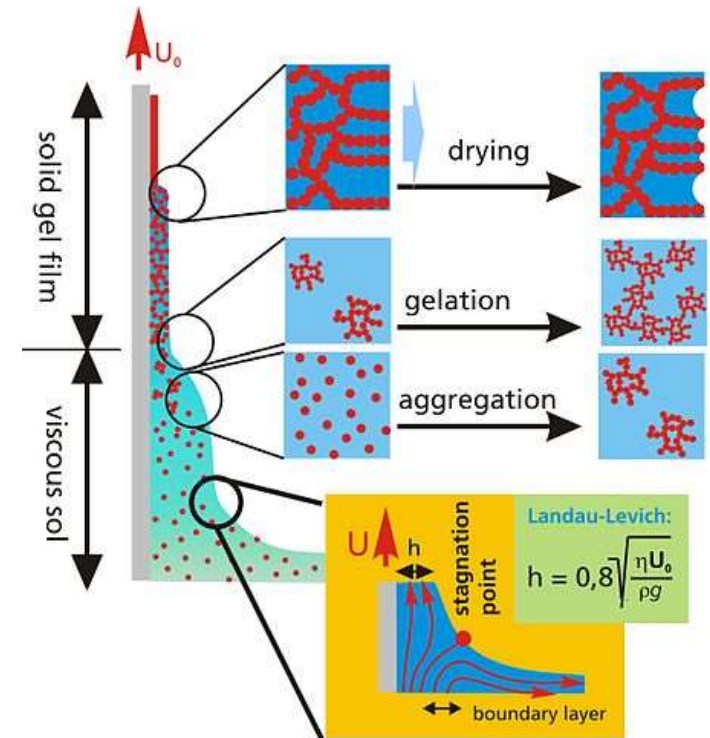


- Peel strength increase as we normalise to ~35µm copper thickness
- No degradation of peel strength up to 40µm overburden
- No adhesion issues when CMP required

# Plating on Glass

## Conclusions – Adhesion Promoter

- The use of VitroCoat provides excellent adhesion to ultra smooth glass
- Ultra thin AP (~10nm) also provide good adhesion (6N/cm)
- Independent of glass type and roughness
- Adhesion is sufficient to withstand
  - Stresses created by electroless copper
  - Stresses created by electrolytic copper
  - Thermal stresses, both reflow and HAST
  - CMP processing
- Without issues with through holes
  - Tested down to 20µm diameter 10:1 AR
- Without issues with blind micro vias
  - Blind vias down to 35µm diameter 2:1 AR



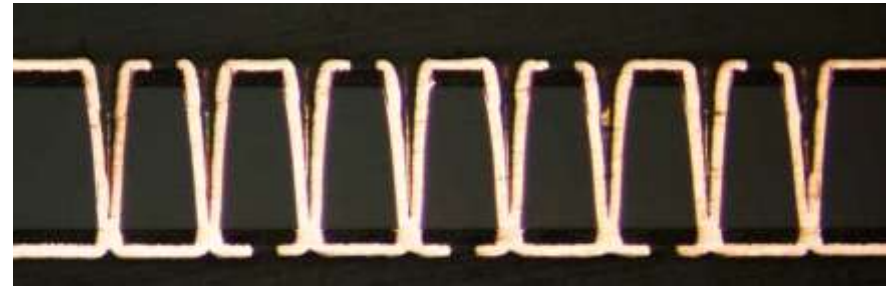
Principle of Sol Gel Process (Dip Coating)

# Plating on Glass

## Electroless Copper and Electrolytic Copper Plating

### Process is Plating Tool and Electrolyte Dependant

- Hole Shape
  - V shaped holes will always fill “bottom up” like a blind micro via
  - Pulse parameters will have to be optimized for these hole shapes
  - Iron mediated electrolytes will offer best chance for success
- No Industry Capability Yet Established
  - Plating tools in IC Substrate manufacturing
  - Conformal plating, and through hole filling
  - Untested as yet on thin glass



Produced in Vertical Plating Systems at Georgia Tech

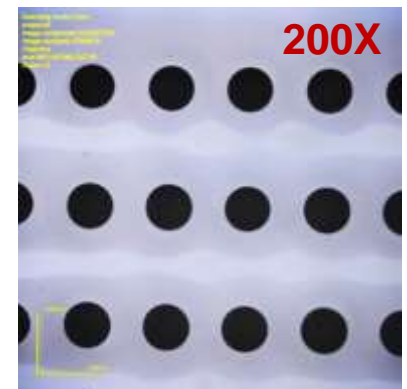
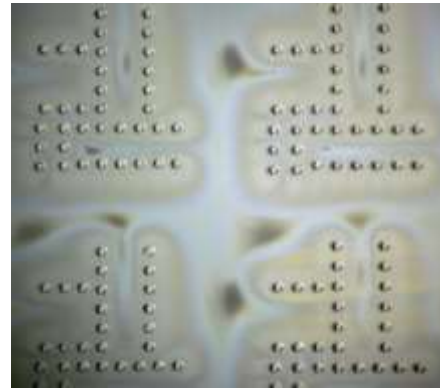
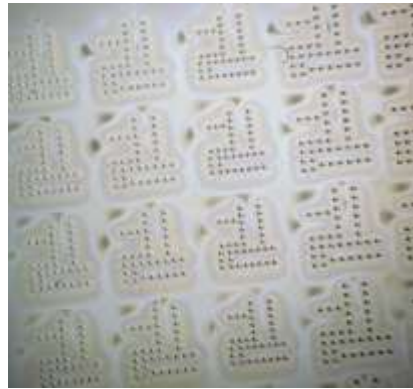


60-25 Hole Ø Top/Bottom - 100µm Glass  
15µm ZIF Polymer - 22µm Cu Overburden

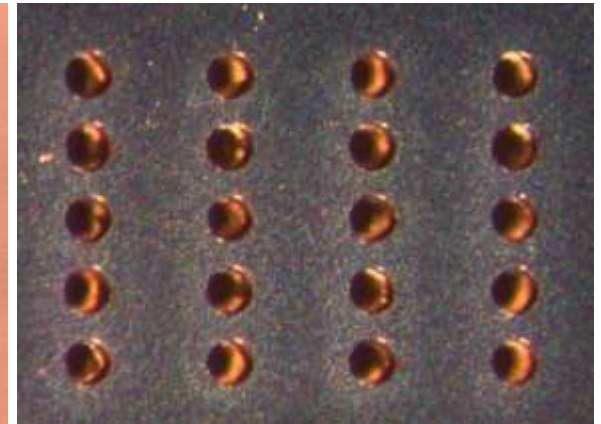
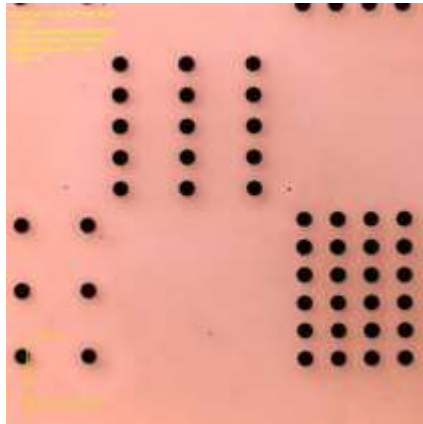
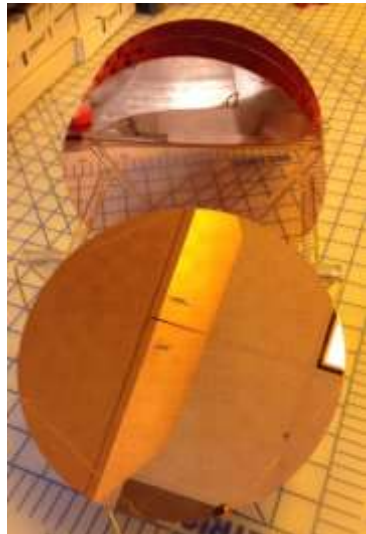
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# Plating on Glass

## Electroless Copper and Electrolytic Copper Plating



**Glass Coated with Adhesion Promoter and Sintered**



**Electroless Copper and Annealing**

**Post Electrolytic Cu**

***No Through Hole Blockages – No Blistering or Adhesion Loss!***

# Plating on Glass

## Electroless Copper and Electrolytic Copper Plating



- Double sided plating using reverse pulse plating with insoluble anodes and an iron redox system
- Void free filling with low surface overburden required
- Challenges
  - Thin and fragile substrates
  - Non-Cylindrical tapered vias with aspect ratios  $> 3:1$  AR



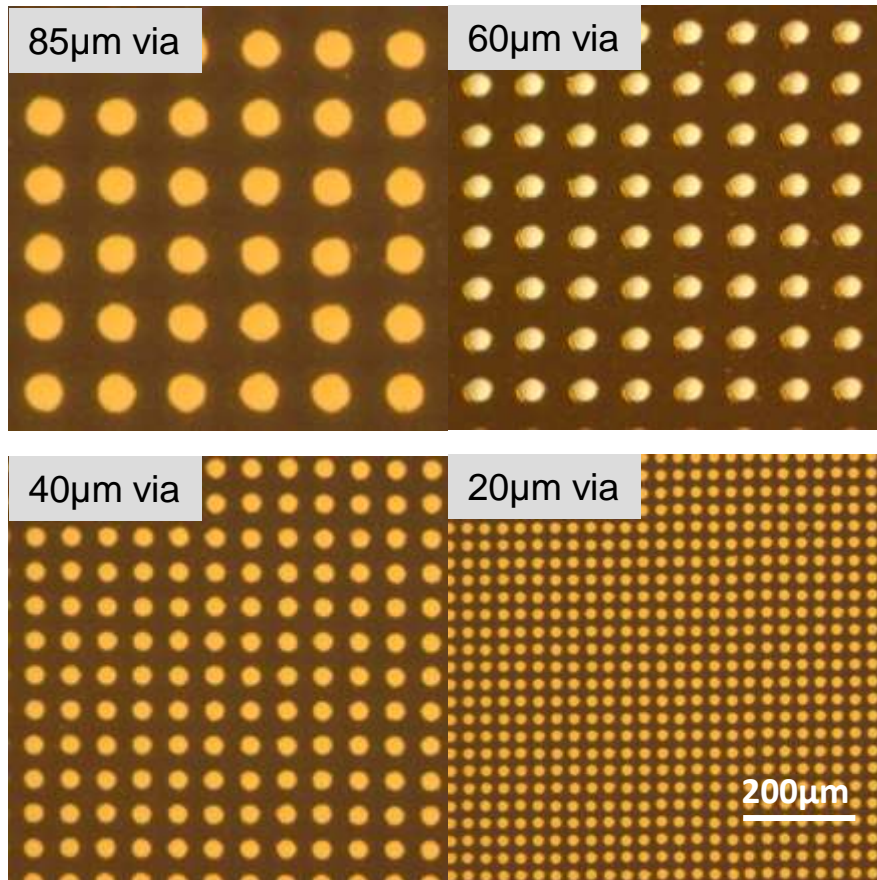


# Plating on Glass

## Electroless Copper and Electrolytic Copper Plating

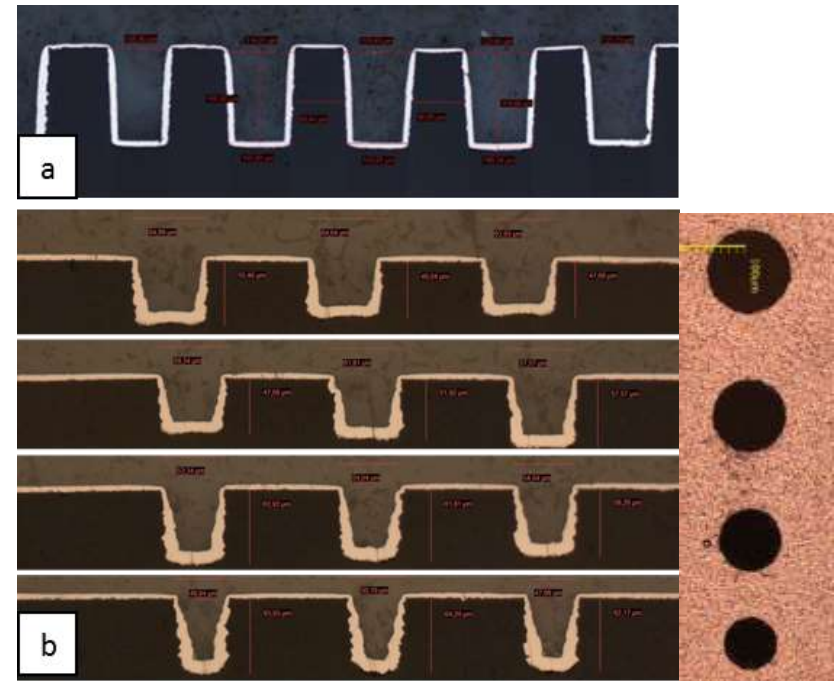
### Through Glass Via (TGV's) Plating

Top view of TGVs (200 or 300µm Glass)



### Blind Micro Via (BMV's) Plating

(a)  $\varnothing 120\mu\text{m} \times 170\mu\text{m}$ ,  
(b)  $\varnothing 65 \sim 35\mu\text{m} \times 60\mu\text{m}$ .



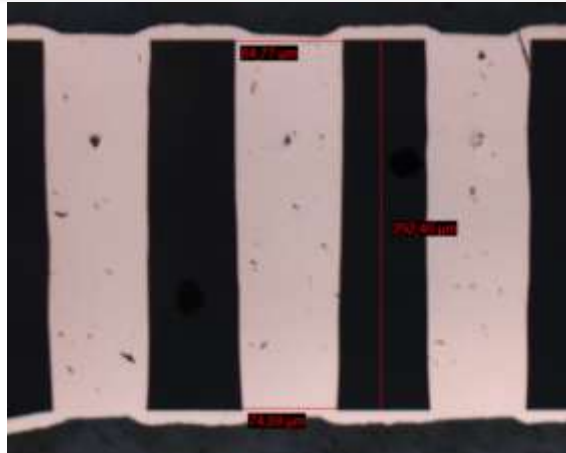
***No Through Hole Blockages – No Blistering or Adhesion Loss!***



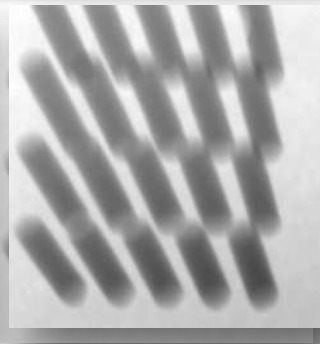
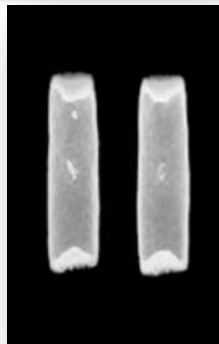
# Plating on Glass

## Through Hole Filling and Blind Via Filling Status

TGV's

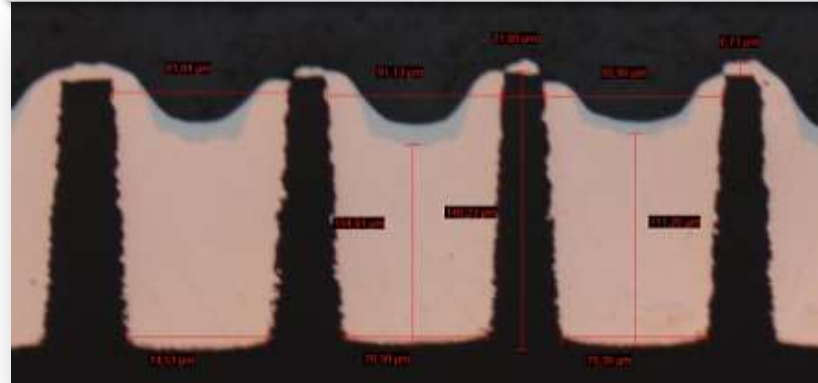


300µm by ~ Ø 80 µm TGV 3.6: 1 AR

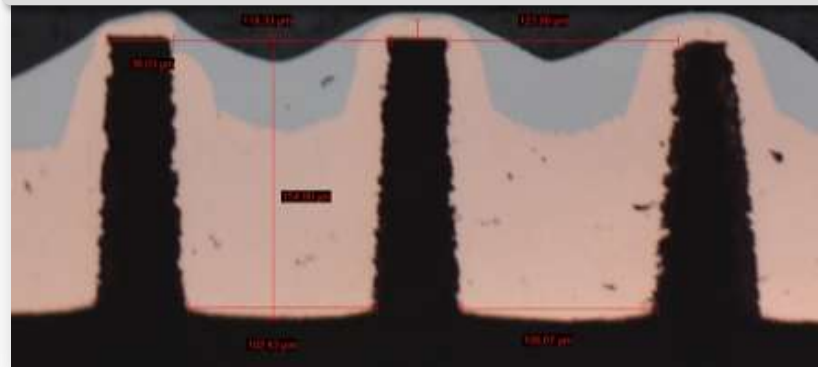


BMV's

170 by Ø 90µm BMV



170 by Ø 120µm BMV

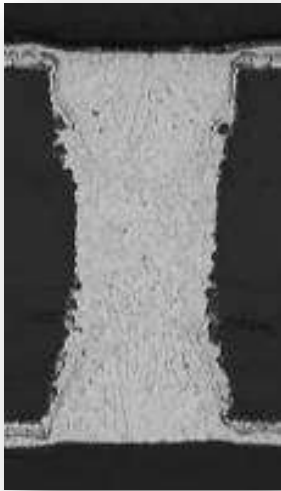
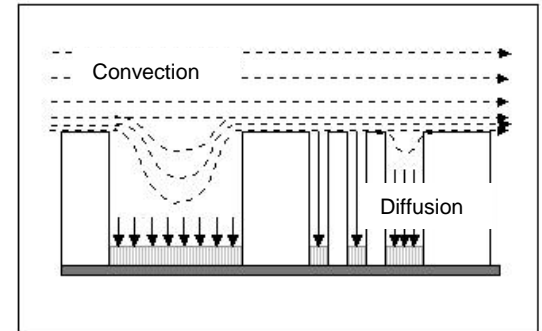


- Copper overburden ~ 10µm, some optimisation still required

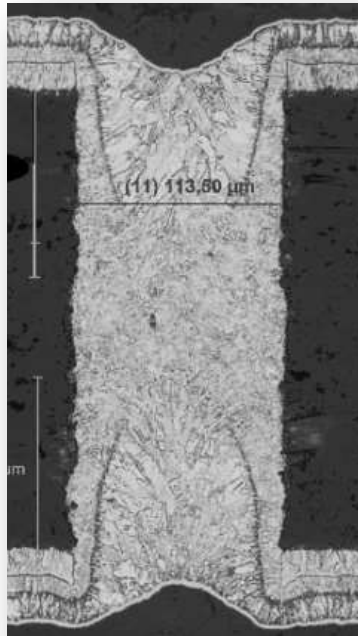
# Plating on Glass

## Multiplate Through Hole Filling Scaling

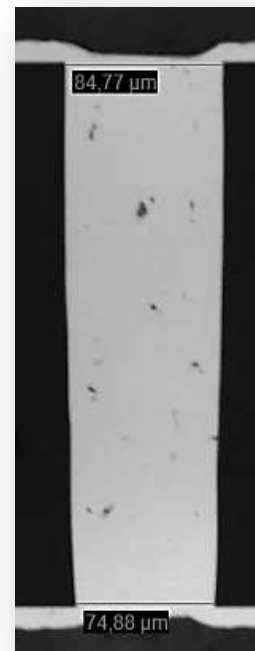
- Feasibility studies for Scaling of THF Approach



200 x 100  $\mu\text{m}$   
Panel Plating



275 x 115  $\mu\text{m}$   
Std. BTT-SC



300 x 80  $\mu\text{m}$   
PoG (3.6 : 1 AR)



295 x 45  $\mu\text{m}$   
CNSE (6.5 : 1 AR)

*New X-Bridging Approach*



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# Electrical Characterisation Fine Line Patterning



# Plating on Glass

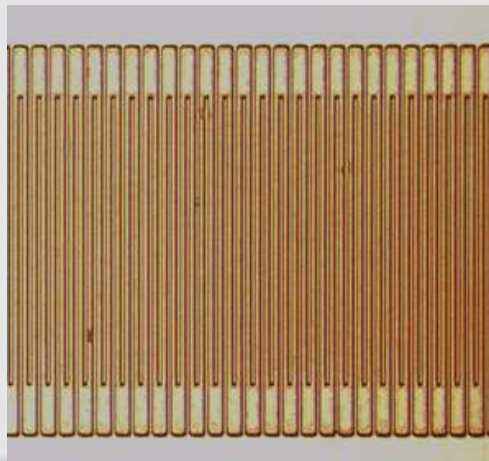
## Initial Fine Line Patterning Results SAP on Glass

Source: Georgia Tech

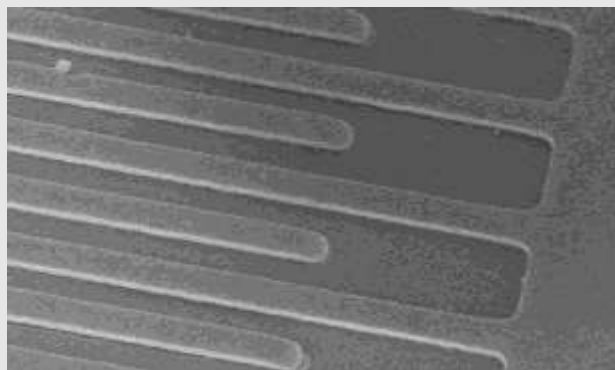
### Process Flow

- Substrate cleaning
- VitroCoat AP coating
- Electroless Cu plating
- Annealing
- Novalink®
- Photolithography
- Electrolytic Cu plating
- Photoresist stripping
- Annealing
- CupraEtch™ DE

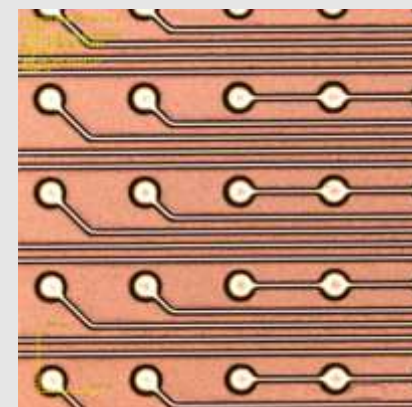
L/S: 6/6µm, Before Cu seed layer etching



L/S=9/9 µm,  
After Cu seed layer etching



150µm Pitch / 50µm Pad  
L/S: 11/11µm,  
Before Cu seed layer etching

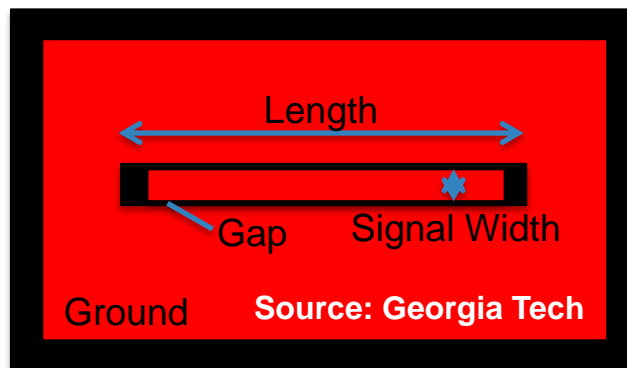


# Plating on Glass

## Coplanar Waveguide (CPW) Design and Sample Fabrication

### CPW Design

- Length
  - 16200, 112000, 6200 $\mu\text{m}$
- Gap
  - 26.5, 19.0 $\mu\text{m}$
- Signal Width
  - 170, 120 $\mu\text{m}$



### Glass Type

- Corning
  - Low CTE glass

### Georgia Tech

- Fabricated, tested
- Within consortium
  - Further tests ongoing

### IZM Cooperation

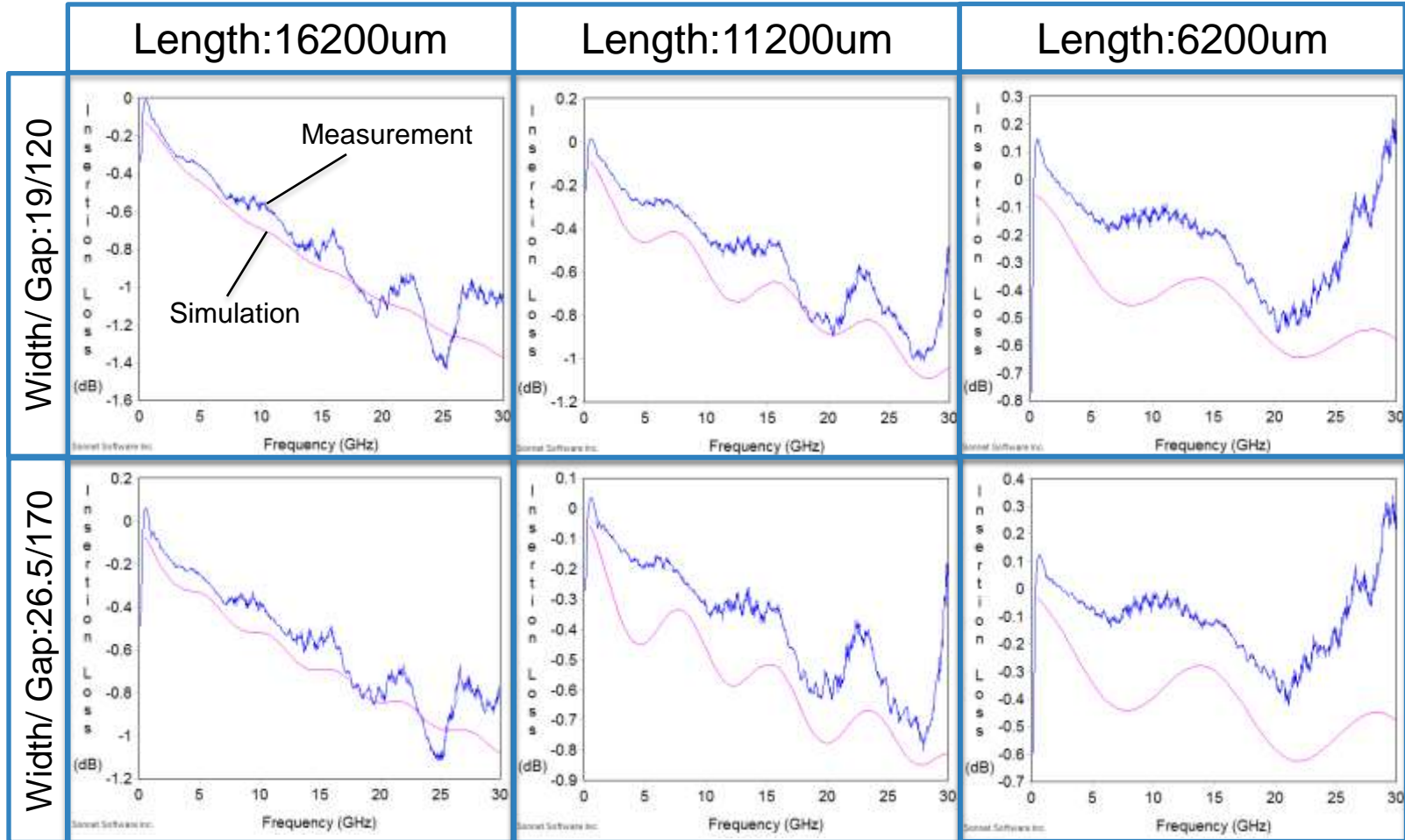
- Demonstrators
- Characterisation

Length / $\mu\text{m}$	Designed		Fabricated		Measurement
	Gap / $\mu\text{m}$	Width / $\mu\text{m}$	Gap / $\mu\text{m}$	Width / $\mu\text{m}$	
16200	26.50	170.00	28.80	167.20	Measurable
16200	19.00	120.00	20.28	117.35	Measurable
11200	26.50	170.00	28.00	168.23	Measurable
11200	19.00	120.00	18.65	120.45	Measurable
6200	26.50	170.00	24.88	169.05	Measurable
6200	19.00	120.00	17.85	118.48	Measurable

# Plating on Glass

## S-Parameters Simulation and Measurement

Source: Georgia Tech



- Good correlation between simulation and measured results
- AP layer has no effect on electrical performance of transmission lines



# Plating on Glass

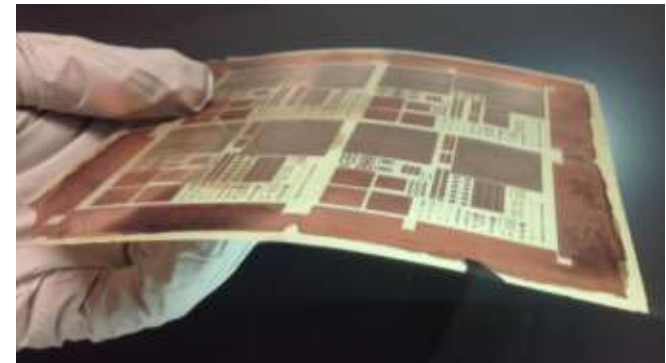
## Summary

- Processes for Glass Interposer Manufacturing are Evolving
  - Adhesion promoter for bare glass developed
  - On bare glass electroless / electrolytic Cu adhesion is the major challenge
- Polymer laminated glass has a POR from Atotech
- Equipment for Glass Interposer Manufacturing
  - Challenge is to handle wet chemical processing of thin glass materials
- Atotech production solutions, horizontal and vertical need to be qualified with thin glass
- Plating parameters / limits must be established
- TCoO, manufacturability and assembly yield will drive market introduction



Atotech's Multiplate System

(Source: Georgia Tech)



30µm Thick Polymer Laminated Glass

***Supporting The Next Generation of Packaging Substrates***



**ATOTECH**

**Thank you for your  
attention!**

